

# P-720 PIFOC® Piezo Nanofocusing Systems

### **Compact High-Dynamics Scanner for Small Objectives**



The P-720 objective nanofocusing / scanning drive (objective not included) was designed for small objectives. Similar PIFOC® systems are available for large objectives and with position sensors

- Travel Range 100 µm
- Rapid Response & Settling Behavior

Max. objective Travel

■ Scans and Positions Objectives with Sub-nm Resolution

Open-loop,

100 μm 0.5 nm

Stiffness

0.2 N/µm

Push/pull

100 / 20 N

force capacity

Rotation

around

 $\theta_{X}, \theta_{Y}$ 

13 µrad

- Frictionless, High-Precision Flexure Guiding System
- Outstanding Lifetime Due to PICMA® Piezo Actuators

ı	Nanopositioning/Piezoelectric			
	Piezo Flexure Stages / High-Speed Scanning Systems			
	Linear			
	Vertical & Tip/Tilt			
	2- and 3-Axis			
	C A			

Linear Actuators & Motors

Fast Steering Mirrors / Active Optics

Piezo Drivers / Servo Controllers

Servo Controllers
Single-Channel

Multi-Channel

Modular

Accessories

Piezoelectrics in Positioning

Nanometrology

Micropositioning

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### objectives. Similar PIFOC® systems are available for large objectives and with position sensors

# P-721K PIFOC® Nosepiece Nanopositioner

### Compact Design, Sub-Nanometer Resolution



Model

P-720.00 25 mm

- Direct-Metrology Capacitive Sensors for Highest Linearity,
   Stability and Control Dynamics
- Frictionless, High-Precision Flexure Guiding System for Better Focus Stability
- Outstanding Lifetime Due to PICMA® Piezo Actuators



Model	Travel	Closed-loop/ open-loop resolution	Resonant frequency (fully loaded)	Dimensions
P-721KTPZ Turret-PIFOC®	80 μm	10 / 0.5 nm	215 Hz	44.5 x 42 x 53 mm (W x L x H)

# P-721K Power-PIFOC® Nosepiece Nanopositioner

## For High-Resolution Microscopy. High-Load Capacity, Capacitive Feedback



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The P-721KPTZ high-load PIFOC® allows precision positioning of a complete microscope turret

- Scans and Positions Objectives with Sub-nm Resolution
- Travel Ranges to 150 µm, Millisecond Settling Time
- Parallel Flexure Guiding for Minimized Objective Offset
- Direct Metrology with Capacitive Sensors for Highest Linearity
- Outstanding Lifetime Due to PICMA® Piezo Actuators

Model	Load capacity	Closed-loop travel	Resonant frequency	Mass
P-721KPTZ	20 N	to 150 μm	410 Hz (no load)	1.5 kg

### P-720

### PIFOC® High-Speed Microscope Objective Nanofocusing/Scanning Z-Drives



P-720 objective nanofocusing / scanning drive (objective not included)

- Scans and Positions Objectives with Sub-nm Resolution
- Low Inertia for Fast Settling
- Frictionless Precision Flexure Guiding System
- Travel to 100 µm
- Straightness of Travel ≤13 μrad
- PICMA® High-Performance Piezo Drives

P-720 PIFOCs® are high-speed, piezo-driven microscope objective nanofocusing/scanning devices which can be mounted on most microscopes. The frictionless, flexure guiding system combines high guiding precision for superior focus stability with fast response for rapid settling and scanning. The units are screwed between

the turret and the objective, providing a positioning and scanning range of up to 100 µm with sub-nanometer resolution, while extending the optical path by only 13 mm (infinity-corrected microscope required; extension tubes are available to adjust path lengths of other objectives on the turret). The standard thread is W0.8  $\times$  1/36", for alternate threads see the P-721.CLQ. For larger positioning ranges, to 460 µm, see the P-725, page 2-22.

#### **Application Examples**

- Scanning interferometry
- Surface structure analysis
- Disk drive testing
- Autofocus systems
- Confocal microscopy
- Biotechnology
- Semiconductor test equipment

#### Operation

The P-720 open-loop PIFOC® is designed for fast, high-resolution positioning and scanning tasks where the absolute position is not important or where an external sensor is used. The vertical position of the objective is roughly proportional to

the drive voltage (see p. 4-15 ff. in the "Tutorial: Piezoelectrics in Positioning" section for behavior of open-loop piezos). If absolute position control, high linearity, or repeatability in the nanometer range is required, refer to the P-721 and

### **Working Principle / Reliability**

pages 2-20 and 2-22).

P-725 closed-loop devices (see

PIFOCs® are equipped with the award winning PICMA® piezo drives, integrated into a sophisticated flexure guiding system. The wire-EDM-cut flexures are FEA modeled for zero stiction, zero friction and exceptional guiding precision. The ceramic-encapsulated PICMA® drives are more robust than conventional piezo actuators, featuring superior lifetime and performance in both dynamic and static applications.

### Notes

See the "Selection Guide" on p. 2-14 ff. for comparison with other nanopositioning systems.

### **Ordering Information**

#### P-720.00

PIFOC® Objective Positioner & Scanner, 100 μm, W0.8 x 1/36"

For PIFOC® Objective Positioners & Scanners with direct metrology and travel ranges to 400  $\mu$ m see P-721 and P-725, p. 2-20 and p. 2-22

#### P-720.01

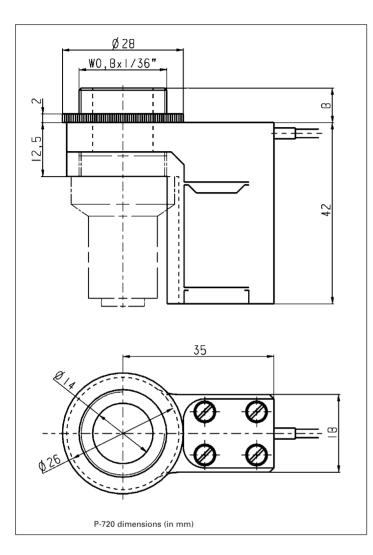
Objective extension tube, 13 mm

Ask about custom designs!



P-721 on a microscope turret







Custom PIFOC® nosepiece nanopositioner for microscope turret.

### Piezo Actuators

# Nanopositioning & Scanning Systems

Active Optics / Steering Mirrors

Tutorial: Piezoelectrics in Positioning

Capacitive Position Sensors

Piezo Drivers & Nanopositioning Controllers

Hexapods / Micropositioning

Photonics Alignment Solutions

Motion Controllers

Ceramic Linear Motors & Stages

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### **Technical Data**

Models	P-720.00	Units	Notes see p. 2-84
Max. objective diameter	25	mm	
Open-loop travel @ 0 to 100 V	100	μm ±20%	A2
* Open-loop resolution	1	nm	C1
Stiffness	0.2	N/μm ±20%	D1
Push/pull force capacity (in operating direction)	100 / 20	N	D3
Tilt $(\theta_X, \theta_Y)$ (typ.)	13	μrad	E1
Lateral runout (Y) (typ.)	100	nm	E2
Electrical capacitance	3.0	μF ±20%	F1
** Dynamic operating current coefficient (DOCC)	3.8	μΑ/(Hz 3 μm)	F2
Unloaded resonant frequency	400	Hz ±20%	G2
Resonant frequency @ 120 g load	180	Hz ±20%	G3
Resonant frequency @ 200 g load	150	Hz ±20%	G3
Operating temperature range	-20 to 80	°C	H2
Voltage connection	VL		J1
Weight (with cables)	100	g ±5%	
Body material	Al		L
Recommended driver/controller (codes explained p. 2-17)	G, C, (A)		

<sup>\*</sup> For calibration information see p. 2-8. Resolution of PI piezo nanopositioners is not limited by friction or stiction. The value given is noise equivalent

given is noise equivalent motion with E-503 amplifier.

\*\* Dynamic Operating Current Coefficient in µA per Hz and µm. Example:
Sinusoidal scan of 30 µm at 10 Hz requires approximately 1.2 mA drive current.

## PIFOC® Objective Scanning System

### **High-Dynamics Sub-Nanometer Piezo Drive; Controller & Software**





PIFOC® long range objective scanning system with QuickLock thread adapter and controller (objective not included)

- Complete System with Controller: Fast Digital Controller, Software-Configurable Servo Parameters
- Travel Range 100 µm
- Scans and Positions Objectives with Sub-nm Resolution
- Frictionless, High-Precision Flexure Guiding System for Better Focus Stability
- Higher Linearity and Stability Through Digital Control and Direct Metrology with Capacitive Sensors
- Clear Aperture up to 29 mm Ø, QuickLock Adapter for Easy Attachment
- Interfaces: USB, RS-232 and analog
- Comprehensive Software Package, Compatible with MetaMorph Imaging Software

The PIFOC® piezo objective scanner systems include a high precision piezo mechanism and a custom-tuned compact digital controller. This combination provides higher performance at reduced costs. The integrated, frictionless and stiff piezo flex-

ure drive ensures high stiffness and fast settling times, as well as an exceptional guiding accuracy and response.

The settling time of less than 10 ms increases the throughput and allows rapid Z-stack acquisition.

### **Application Examples**

- Microscopy
- Confocal microscopy
- 3D Imaging
- Screening
- Autofocus systems
- Surface analysis
- Wafer inspection

# Position Measurement with Highly Accurate Capacitive Sensors or Lower-

**Priced Strain Gauge Sensors** 

Capacitive sensors measure the position directly and without contact, they offer therefore a position resolution of far below one nanometer and excellent values in linearity.

As an alternative, compact and lower-priced strain gauge sensors (SGS) with nanometer-

level resolution can be used which are applied to appropriate places on the drive train and thus measure the displacement of the moving part of the stage. The linearity is improved considerably with the digital controller provided.

### Simple Installation with QuickLock Thread Options

The PIFOC® is mounted between the turret and the objective with the QuickLock thread adapter. After threading the adapter into the turret, the QuickLock is affixed in the desired position. Because the PIFOC® body need not to be rotated, cable wind-up is not an issue. For applications which require a particularly large optical aperture a version with a 29 mm diameter threaded inserts is available.

### Digital Controller for Automated Scans

Included in the delivery is a digital controller which opens up the possibilities of digital control for piezo-driven nanopositioning systems for the same price as analog controllers. The advantage: higher linearity, simple operation and access to advanced features.

### **Ordering Information**

### PD72Z1CAA

Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 μm, Capacitive Sensor, M32 Large Aperture QuickLock Thread Adapters, Digital Controller with USB, RS-232

#### PD72Z1CAQ

Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 μm, Capacitive Sensor, M25 QuickLock Thread Adapters, Digital Controller with USB, RS-232

### PD72Z1SAA

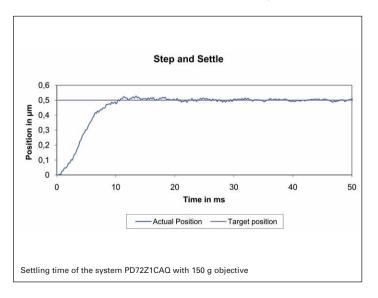
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, SGS Sensor, M32 Large Aperture QuickLock Thread Adapters, Digital Controller with USB, RS-232

### PD72Z1SAQ

Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, SGS Sensor, M25 QuickLock Thread Adapters, Digital Controller with USB, RS-232

# Flexibility: Software Configurable Servo Parameters

All servo controllers require tuning and adjustment of servo parameters for optimum performance (e.g. as a result of changes to the load or the motion profile). With a digital controller, all adjustments are carried out by simple software commands and the resulting motion or transient characteristics can be viewed, analyzed and further optimized immedi-



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ately with the provided software. It is also possible to switch between previously found sets of parameters when the controller is in operation. Since jumpers and potentiometers no longer have to be set manually, system integration becomes much more straightforward.

System setup with the included user-interface software is fast

and easy, interfacing to the customers' software is facilitated with the included LabVIEW drivers and DLLs.

Drivers for MetaMorph and µManager are available.

### **Technical Data**

Active axes         Z         Z           Motion and positioning         Integrated sensor         SGS         Capacitive           Closed-loop travel         100         100           Closed-loop resolution         5         1           Closed-loop linearity         0.2         0.06           Repeatability         ±10         ±5           Runout θX, θY         13         13           CrossTalk in X, Y         100         100           Settling time (0.5 μm step with 5 % accuracy, 150 g)         10         10           Mechanical properties         5         580           Stiffness in motion direction         0.3         0.3           Unloaded resonant frequency         580         580           Resonant frequency @ 120 g         235         235           Resonant frequency @ 200 g         180         180           Push/pull force capacity         100 / 20         100 / 20           in motion direction         100 / 20         100 / 20	ve µm nm			
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Resonant frequency @ 200 g 180 180 Push/pull force capacity 100 / 20 in motion direction	Hz	±20%		
Push/pull force capacity 100 / 20 100 / 20 in motion direction	Hz	±20%		
in motion direction	Hz	±20%		
	N	Max.		
Drive properties				
Ceramic type PICMA® P-885 PICMA®	P-885			
Controller				
Function Digital controller for single-axis piezo nanoposit	Digital controller for single-axis piezo nanopositioning systems			
Processor DSP 32-bit floating point, 150 MHz	DSP 32-bit floating point, 150 MHz			
Communication interfaces USB, RS-232	USB, RS-232			
Linearization 5th order polynomials	5th order polynomials			
Amplifier power 10 W (<5 ms); 5 W (>5 ms)	10 W (<5 ms); 5 W (>5 ms)			
	HD-Sub-D 26-pin, 1 Analog input 0 to 10 V, 1 Sensor monitor 0 to 10 V, 1 digital input (LVTTL, programmable), 5 digital outputs (LVTTL, 3 predefined, 2 programmable)			
User software PIMikroMove, NanoCapture	PIMikroMove, NanoCapture			
Software drivers LabVIEW drivers, DLLs	LabVIEW drivers, DLLs			
Supported functionality  Digital setting of the control parameters, wave compatible to MetaMorph, µManager	Digital setting of the control parameters, wave generator, data recorder, auto zero, trigger I/O; compatible to MetaMorph, µManager			
Display Status LED, overflow LED				
Miscellaneous				
Operating temperature range 10 to 50 10 to 50	°C			
Material scanner Aluminum Aluminum	ım			
Weight 0.22 (scanner), 0.5 (controller) 0.24 (sca	anner), 0.5 (controller) kg	±5%		
Cable length to controller 1 1				
Dimensions controller 160 x 96 x 33 160 x 96	m			



